

oplicant(s):

Tom Tse, et al.

Title:

METHOD AND SYSTEM FOR DOSE CONTROL DURING AN ION

IMPLANTATION PROCESS

App. No.:

10/082,567

Filed:

February 25, 2002

Examiner:

Mary A. El Shammaa

Group Art Unit:

2881

Atty. Dkt. No.: 1458.TT4763

M/S AF Commissioner for Patents PO Box 1450 Alexandria, VA 22313-1450

RESPONSE TO FINAL OFFICE ACTION

Dear Sir:

In response to the Final Office Action mailed November 20, 2003 regarding the above captioned patent application, the Applicants hereby respectfully submit the following amendment and response.

01/26/2004 CHGUYEN 00000012 010365 10082567 06.00 DA 01 FC:1201

CERTIFICATE OF TRANSMISSION/MAILING

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